

FORM PTO-1449  
(REV. 7-80)

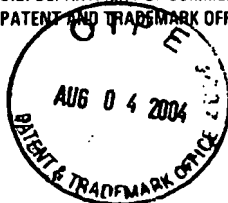
U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO.: 5005.1087

SERIAL NO.: 10/729,588

LIST OF PRIOR ART CITED BY APPLICANT

(Use several sheets if necessary)



APPLICANT(S): Franz CEMIC et al.

FILING DATE: 12/05/2003

GROUP: 2621

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER								DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE
/RIC/	AA	3	8	1	4	5	2	1		June 4, 1974	Free	358	158	
/RIC/	AB	8	3	2	3	9	5	3		Nov. 27, 2001	Blaesing-Bangert et al.	358	614	
/RIC/	AC	20	02	00	57	8	3	9		May 18, 2003	Rinn et al.	382	199	
	AD													
	AE													
	AF													
	AG													
	AH													
	AI													

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
													YES	NO
/RIC/	AJ	1	9	8	1	9	4	92	Nov. 11, 1999	DE-Germany			corresponds to U.S. 6,323,953	
/RIC/	AK	1	0	0	4	7	2	11	May 8, 2002	DE-Germany			corresponds to U.S. 2002/0057839	
	AL													
	AM													
	AN													

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

/RIC/	AO	I.S. GRADSHTEYN and I.M. RYZHIK, "Table of Integrals, Series, and Products", pp. 982-983, Academic Press, New York, 1980												
/RIC/	AP	Nicholas DOE, Richard EANDI, "Optical Proximity Effects in Sub-micron Photomask CD Metrology", pp. 1-16, Advanced Imaging Systems, Zygo Corporation, Sunnyvale, CA 94404, Nov. 99												
/RIC/	AR	Joseph W. GOODMAN, "Frequency Analysis of Optical Imaging Systems", Introduction to Fourier Optics, pp. 101-121, McGraw-Hill, San Francisco, 1963												
	AS													
	AT													

EXAMINER

/Randolph Chu/

DATE CONSIDERED

05/03/2007

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

